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JUL 22 2004

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In re Application of
Selvamanickam, Venkat et al.

Serial Number: 10/602,468

Filed: June 23, 2003

For: METALORGANIC CHEMICAL VAPOR
DEPOSITION (MOCVD) PROCESS AND
APPARATUS TO PRODUCE MULTI-LAYER
HIGH-TEMPERATURE SUPERCONDUCTING
(HTS) COATED TAPE

PETITION UNDER
M.P.E.P. 708.02 IX

This is in response to the petition filed February 12, 2004, requesting that the above-identified application be granted Special Status under Section 708.02 IX of the MPEP and 37 CFR 1.102 (b) (no fee required).

The request for Special Status considered under Section 708.02 IX of the MPEP is granted because the criteria under 37 CFR 1.102(b) has been met.

Accordingly the petition is **GRANTED**.

Marian C. Knode

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